Free Accessible Microchannel Using Air-Liquid Interface with Patterned Nano-Geometric Surface by Hybrid Mask Lithography

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eduction of robot motion disturbance by air-liquid interface



S. Sakuma, M. Sugita, F. Arai, "Hybrid mask exposure for fabrication of micro-pattern with nano-pillars", IEEE International Conference on Nano/Micro Engineered and Molecular Systems (NEMS), pp.72-75, 2012.

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